

RESPONSE UNDER 37 CFR 1.116 EXPEDITED PROCEDURE EXAMINING GROUP 2851

00862.022246

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
	:	Examiner: H. Nguyen
Kazunori IWAMOTO et al.)	
	:	Group Art Unit: 2851
Application No.: 09/866,600)	_
	:	Confirmation No.: 4961
Filed: May 30, 2001)	
For: STAGE APPARATUS WHICH SUPPORTS	:	October 8, 2003
INTERFEROMETER, STAGE POSITION	:	,
MEASUREMENT METHOD, PROJECTION)	
EXPOSURE APPARATUS, PROJECTION	:	
EXPOSURE APPARATUS MAINTENANCE)	
METHOD, SEMICONDUCTOR DEVICE	:	
MANUFACTURING METHOD, AND)	
SEMICONDUCTOR MANUFACTURING FACTORY	:	

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Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL REJECTION

Sir:

In response to the Official Action dated July 8, 2003, please amend the above-identified application as follows:

10/09/2003 SSITHIB1 00000041 09866600 01 FC:1201 86.00 0P